

MPI TS2000-SE | 200 mm Automated Probe System with ShieldEnvironment™

Innovation - Integration - Revolution - for most accurate and reliable DC/CV, RF and mmW measurements

ShieldCap™

- Consequent shielding and easy re-configuration
- Allows up to 4-port RF or up to 8-ports DC/Kelvin or a combination of those configurations
- Probe card version available

Probe Platen

- Stable and rigid design
- Rectangular adjustments for RF positioners
- Integrated air-cooling for maximum thermal stability
- Unique access for maintenance and service

ShieldEnvironment™

- Excellent EMI- and light-tight shielded test environment for ultra-low noise, low capacitance measurements
- Front door for manual loading of IC or wafers

Modular Chucks

- Various non-thermal or thermal chucks
- Choice of Triaxial or Coaxial connection
- Wide range of temperature from -60 °C up to 300 °C
- Field upgradable for reduced cost of ownership

RF Calibration

- 2 auxiliary chucks for calibration substrates
- Built-in ceramic for accurate calibration
- 1 µm flatness for consistent contact quality

Safety Test Management™ (STM) System

- Provides unique safety, reliable and convenient environment for testing at different temperatures
- Intelligent dew point control routine avoids acumination during cold testing
- Automatically monitoring the flow of CDA or Nitrogen
- If the flow is interrupt or insufficient the STM™ turns the chuck automaticall into a safe mode

Active Vibration Isolation

- Incorporates a high performance vibration isolation platform
- Optimized total footprint
- Optional instrument shelf reduces cable lengths and increases measurement dynamic and directivity

mDrive™ Option

- Provides a truly intuitive, manual operation of all existing programmable stages, such as chuck, scope or MicroPositioners
- X- and Y-axis fine control for the selected stage
- Z safety function requires additional enabling

Probe Hover Control PHC™ Option

- Manual control of probes to wafer contact & separation
- Visual feedback down to 1 µm accuracy in SENTIO®

Microscope and Optics Options

- Stable microscope bridge mount with 50 x 50 x 140 mm programmable movement
- Various optics options available such as MPI AMZ12 w. up to 12x optical zoom or MPI iMAG® - the digital microscope

Software Suite SENTIO®

- Simple and intuitive operation by revolutionary, multi-touch software control saves significant training time
- Scroll, Zoom, Move commands mimic modern smart mobile devices and allows to become an expert in just minutes
- Switching between the active application and the rest of the APPs is just matter of a simple finger sweep
- MPI RF calibration software program QAlibria® is fully integrated with SENTIO® - for ease of use by following a single operational concept methodology
- GPIB, TCP/IP interface for remote control

Thermal Control

- Thermal chuck can be operated by using the fully integrated touch-screen display
- placed at convenient location in front of the operator for fast operation and immediate feedback

Automated single wafer loader

- Very convenient wafer loading with easy pre-alignment for automated routines
- Loading or unloading of 100, 150 or 200 mm wafer is straight forward and intuitive

Hot/cold wafer swaps at set temperatures

- Unique capability to load/unload wafers at any chuck temperatures
- Saves major down time and increases the overall MPI Test Systems efficiency significantly

Integrated Hardware Control Panel

- Provide faster, safer and convenient system control and test operation
- The Keyboard and mouse are strategically located to control the software if necessary and will also control the Windows® based instrumentation

Vertical Controlled Environment™ (VCE) Option

- Automated side view of the probe tips - the VCE™ allows contact position automation independent of the probe card tip-drop
- This enables working with probe cards, either DC or RF, very safe, especially inside the MPI ShieldEnvironment™

